AMENDMENTS TO THE CLAIMS:

Claims 1-13 (Cancelled)

14. (New) A scanning electron microscope comprising:

a focusing lens for focusing a primary electron beam on a sample when a low-magnification mode is set;

an objective lens for focusing the primary electron beam on the sample when a high-magnification mode is set;

an X-ray detector for detecting an X-ray emitted from the sample; and

a processing unit for controlling the object lens to prevent reflected electrons from entering the X-ray detector when the low-magnification mode is set.

15. (New) A scanning electron microscope having an X-ray detector for detecting an X-ray and a secondary electron detector for detecting secondary electrons, the microscope comprising:

an object lens for generating a magnetic field, wherein the magnetic field is changed automatically in accordance with detection of the X-ray or the secondary electrons, and the magnetic field prevents an incidence of reflected electrons to the X-ray detector when the X-ray is detected.

16. (New) A scanning electron microscope an X-ray detector for detecting an X-ray and a secondary electron detector for detecting secondary electrons, the microscope comprising:

an objective lens for focusing a primary electron beam or for preventing an incidence of reflected electrons, wherein a parameter related to the object lens is adjusted automatically in accordance with a change of X-ray detection and secondary electron detection.

AMENDMENTS TO THE DRAWINGS:

Please replace Fig. 2 with the attached new Fig. 2. Fig. 2 is amended to change the label "BRIGHTNESS" under the description box for the upper curve to "IMAGE BRIGHTNESS," and the labels "BRIGHTNESS REGION" in boxed description to the lower curve and next to the right axis are changed to "REGION BRIGHTNESS."